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CONFIRMATION NO. 7107

SERIAL NUMBER 10/527,642	FILING OR 371(c)	CLASS 438		GROUP ART UNIT 2812		ATTORNEY DOCKET NO. 267410US26PCT		
APPLICANTS Masanobu Igeta, Yamanashi, JAPAN; Shintaro Aoyama, Yamanashi, JAPAN; Hiroshi Shinriki, Chiba, JAPAN; ***CONTINUING DATA ************************ This application is a 371 of PCT/JP03/11971 09/19/2003 ***FOREIGN APPLICATIONS ************************************								
Foreign Priority claimed			STATE OR COUNTRY JAPAN	DRAWING CL		CLAI	TOTAL INDEPENDENCLAIMS 20 5	
ADDRESS 22850 TITLE								
Method for forming insulating film on substrate, method for manufacturing semiconductor device and substrate- processing apparatus								
FILING FEE RECEIVED No to charge/credit DEPOSIT ACCOUNT No for following:				All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other Credit				